



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of:

Attorney Docket No.: 2950.16US02

BI et al.

Confirmation No.: 9146

Application No.: 09/715,935

Examiner: Eric B. Fuller

Filed: November 17, 2000

Group Art Unit: 1762

For: COATING FORMATION BY REACTIVE DEPOSITION

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SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 C.F.R. § 1.56, and in addition to information disclosed in Applicant's Information Disclosure Statement filed March 22, 2001 and March 25, 2002, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached Form PTO-1449. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed before the mailing date of a first Office Action along with the filing of a Request for Continued Examination under 37 C.F.R. § 1.114.

Respectfully submitted,



Peter S. Dardi, Ph.D.  
Registration No. 39,650

Customer No. 24113  
Patterson, Thunte, Skaar & Christensen, P.A.  
4800 IDS Center  
80 South 8th Street  
Minneapolis, Minnesota 55402-2100  
Telephone: (612) 349-5746

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Peter S. Dardi  
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Substitute for form 1449/PTO  <b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b> <i>(Use as many sheets as necessary)</i>			<i>Complete if Known</i>		
			Application Number	09/715,935	
			Filing Date	November 17, 2000	
			First Named Inventor	BI et al.	
			Art Unit	1762	
			Examiner Name	Eric B. Fuller	
			Attorney Docket Number	2950.16US02	
Sheet	1	of			

### U.S. PATENT DOCUMENTS

EXAMINER INITIAL*	Cite No. <sup>1</sup>	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document
		Number-Kind Code <sup>2</sup> (if known)		
		US-4,581,248	04/08/1986	Roche
		US-4,681,640	07/21/1987	Stanley
		US-4,782,787	11/08/1988	Roche
		US-5,085,166	02/04/1992	Oka et al.
		US-5,174,826	12/29/1992	Mannava et al.
		US-5,246,745	09/21/1993	Baum et al.
		US-5,306,447	04/26/1994	Marcus et al.
		US-5,652,021	07/29/1997	Hunt et al.
		US-5,858,465	01/12/1999	Hunt et al.
		US-6,013,318	01/11/2000	Hunt et al.
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### FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL*	Cite No. <sup>1</sup>	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	T <sup>6</sup>
		Country Code <sup>3</sup> Number <sup>4</sup> Kind Code <sup>5</sup> (if known)			

EXAMINER SIGNATURE	DATE CONSIDERED
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INFORMATION DISCLOSURE  
STATEMENT BY APPLICANT

(Use as many sheets as necessary)

Application Number	09/715,935
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Art Unit	1762
Examiner Name	Eric B. Fuller
Attorney Docket Number	2950.16US02

Sheet 2 of 3

## NON PATENT LITERATURE DOCUMENTS

EXAMINER INITIAL*	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T <sup>2</sup>
		BESLING et al., Laser-Induced Chemical Vapor Deposition of Nanostructured Silicon Carbonitride Thin Films, 1997, pp. 544-553, Laboratory for Applied Inorganic Chemistry, Delft University of Technology, Julianalaan 136, 2628 BL Delft, The Netherlands.	
		BILENCHI et al., CO <sub>2</sub> Laser-Assisted Deposition of Boron and Phosphorus-Doped Hydrogenated Amorphous Silicon, American Institute of Physics 1985, pp. 279-281.	
		BILENCHI et al., Hydrogenated Amorphous Silicon Growth by CO <sub>2</sub> Laser Photodissociation of Silane, American Institute of Physics 1982, pp. 6479-6481.	
		BORNARD et al., LiNbO <sub>3</sub> Thin Films Deposited on Si Substrates: a Morphological Development Study, Materials Chemistry and Physics, pp. 571-577, Elsevier Science B.V. 2002.	
		ICHINOSE et al., Deposition of LaMO <sub>3</sub> (M=Co, Cr, Al) Films by Spray Pyrolysis in Inductively Coupled Plasma, Journal of Crystal Growth, pp. 59-64, Elsevier Science B.V. 1994.	
		ICHINOSE et al., Deposition of LaMO <sub>3</sub> (M=Co, Cr, Al)-Oriented Films by Spray Combustion Flame Technique, Jpn. J. Appl. Phys. Vol. 33 (1994), pp. 5907-5910.	
		JERVIS, Metal Film Deposition by Gas-Phase Laser Pyrolysis of Nickel Tetracarbonyl, American Institute of Physics 1985, pp. 1400-1401.	
		KIM et al., Deposition of MgO Thin Films by Modified Electrostatic Spray Pyrolysis Method, Thin Solid Films 376 (2000), pp. 110-114, Elsevier Science S.A. 2000.	
		MAGEE et al., Laser-Induced Conversion of Molecular Precursors to Thin Films and Deposited Layers, American Chemical Society 1990, pp. 232-235.	
		MARIC et al., Electrolyte Materials for Intermediate Temperature Fuel Cells Produced via Combustion Chemical Vapor Condensation, Electrochemical and Solid-State Letters, 6 (5) 2003, pp. A91-A95.	
		MEUNIER et al., Hydrogenated Amorphous Silicon Produced by Laser Induced Chemical Vapor Deposition of Silane, American Institute of Physics 1983, pp. 273-275.	
		MEUNIER et al., Laser-Induced Chemical Vapor Deposition of Hydrogenated Amorphous Silicon. I. Gas-Phase Process Model, American Institute of Physics 1987, pp. 2812-2821.	
		MEUNIER et al., Laser-Induced Chemical Vapor Deposition of Hydrogenated Silicon. II. Film Properties, American Institute of Physics 1987, pp. 2822-2829.	

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SIGNATUREDATE  
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		OLJACA et al., Deposition of Ba <sub>x</sub> Sr <sub>1-x</sub> TiO <sub>3</sub> in Atmospheric Pressure Flame: Combustion Monitoring and Optimisation of Thin Film Properties, Surface Engineering, Vol. 19, No. 1, 2003, pp. 51-57.			
		VUKASINOVIC et al., Closed Loop Controlled Deposition of Ba <sub>x</sub> Sr <sub>1-x</sub> TiO <sub>3</sub> Thin Films in Spray Flames, Surface Engineering, Vol. 19, No. 3, 2003, pp. 179-184.			
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<p>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. <sup>1</sup>Applicant's unique citation designation number (optional). <sup>2</sup>Applicant is to place a check mark here if English language Translation is attached.</p> <p>This collection of information is required by 37 CFR 1.98. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 120 minutes to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, Washington, DC 20231. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: <b>Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450.</b></p> <p style="text-align: center;"><i>If you need assistance in completing the form, call 1-800-PTO-9199 (1-800-786-9199) and select option 2.</i></p>					